WHAT IS CLAIMED IS:

1. A method of forming a liquid crystal layer on a substrate having a sealed pattern, comprising:

preparing a liquid crystal material in a projecting portion;

applying a vibration and pressure to the projecting portion so as to emit the liquid crystal material from the projecting portion; and

depositing the emitted liquid crystal material on the substrate.

- 2. The method according to claim 1, wherein the projecting portion has a nozzle plate containing a plurality of orifices, said nozzle plate adjusting the applied pressure for emitting the liquid crystal material, said liquid crystal material being emitted through the plurality of orifices.
- 3. The method according to claim 1, wherein the substrate moves in one direction while the liquid crystal material is being deposited thereon.
- 4. The method according to claim 1, wherein the liquid crystal material is emitted and deposited in a vacuum chamber.
- 5. The method according to claim 1, wherein the vibration is generated by a voltage applied to a resonator.

- 6. The method according to claim 5, wherein the generated vibration is transmitted to the projecting portion through a resonating plate.
- 7. The method according to claim 1, wherein the substrate has a black matrix under the sealed pattern.
- 8. The method according to claim 7, wherein the liquid crystal material start and stop is deposited on the black matrix.
- 9. An apparatus of forming a liquid crystal layer on a substrate having a seal pattern, comprising:
 - a projecting portion having a liquid crystal material;
 - a resonator for generating a vibration; and
- a resonating plate for transmitting the vibration to the projecting portion.
- 10. The apparatus according to claim 9, wherein the projecting portion has a nozzle plate containing a plurality of orifices, the nozzle plate adjusting the applied pressure for emitting the liquid crystal material, the liquid crystal material being emitted through said plurality of orifices.
- 11. The apparatus according to claim 9 wherein the substrate is mounted on a stage.

- 12. The apparatus according to claim 11, wherein means are provided for moving the stage.
- 13. The apparatus according to claim 9, further comprising a vacuum chamber for encompassing the projecting portion, the resonator and the resonating plate.
- 14. The method according to claim 9, wherein voltage means are provided for generating vibration in the resonator.